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(12) **United States Design Patent**
Ishibashi et al.

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(54) **ROLLER SHAFT FOR SEMICONDUCTOR
CLEANING**

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** **25-03**

(52) **U.S. Cl.**
USPC **D32/25**

(58) **Field of Classification Search**
USPC D32/1, 25, 35; 15/77, 102, 230, 230.12,
15/230.14, 230.16; 134/6; 451/194
See application file for complete search history.

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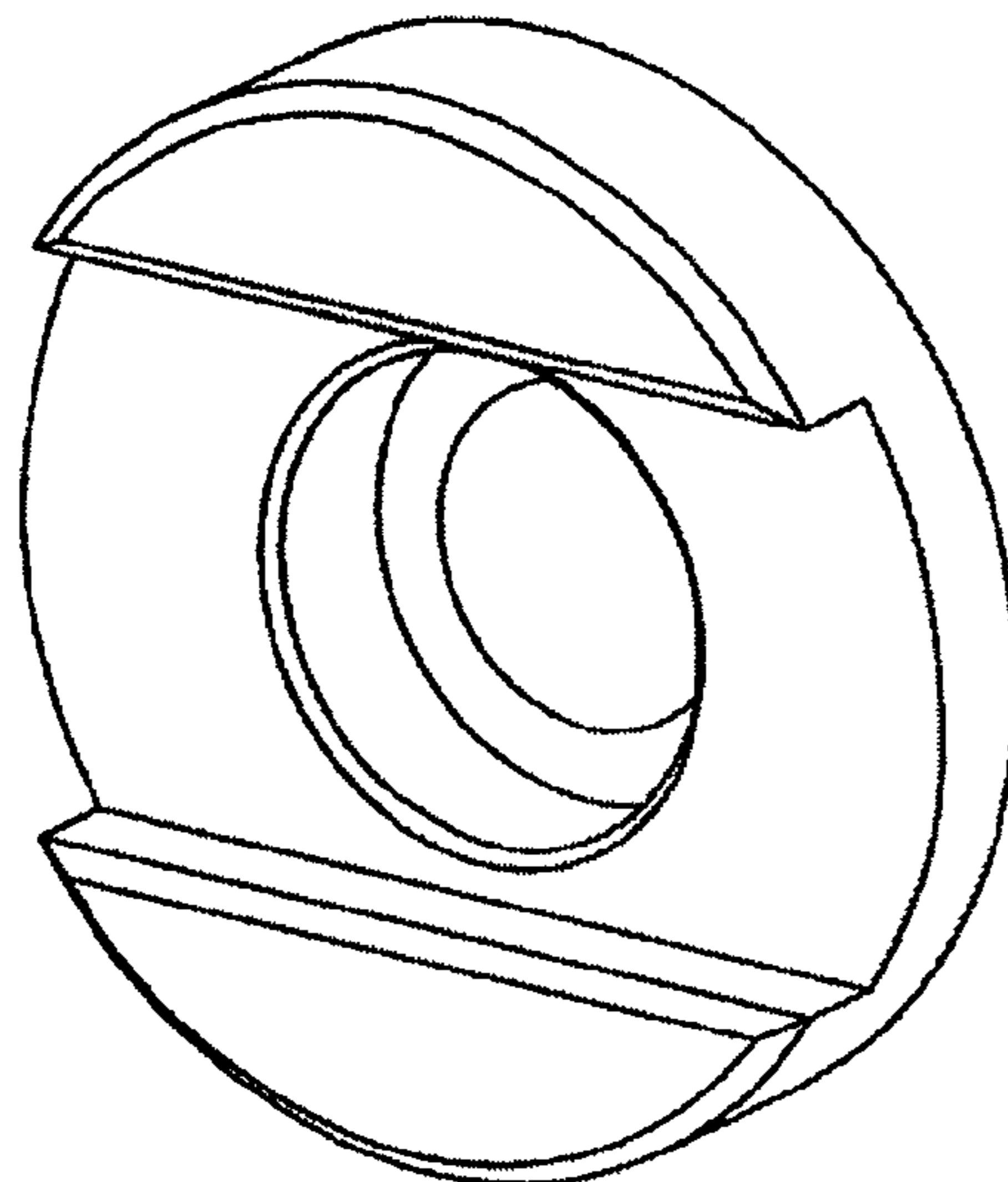
(57) **CLAIM**

We claim the ornamental design for a roller shaft for semiconductor cleaning, as shown and described.

DESCRIPTION

FIG. 1 is a front elevational view of a roller shaft for semiconductor cleaning showing our new design;
 FIG. 2 is a rear elevation view thereof;
 FIG. 3 is a top plan view thereof, the bottom view being a mirror image thereof;
 FIG. 4 is a right side view thereof, the left side view being a mirror image thereof;
 FIG. 5 is a cross sectional view taken along the line 5-5 of FIG. 1;
 FIG. 6 is a front perspective view, at an enlarged scale;
 FIG. 7 is a front elevational view thereof, at an enlarged scale;
 FIG. 8 is an enlarged view of the area 8 seen in FIG. 3; and,
 FIG. 9 is an enlarged view of the area 9 seen in FIG. 4.
 The broken line showing depicts environmental subject matter only and forms no part of the claimed design.

1 Claim, 9 Drawing Sheets



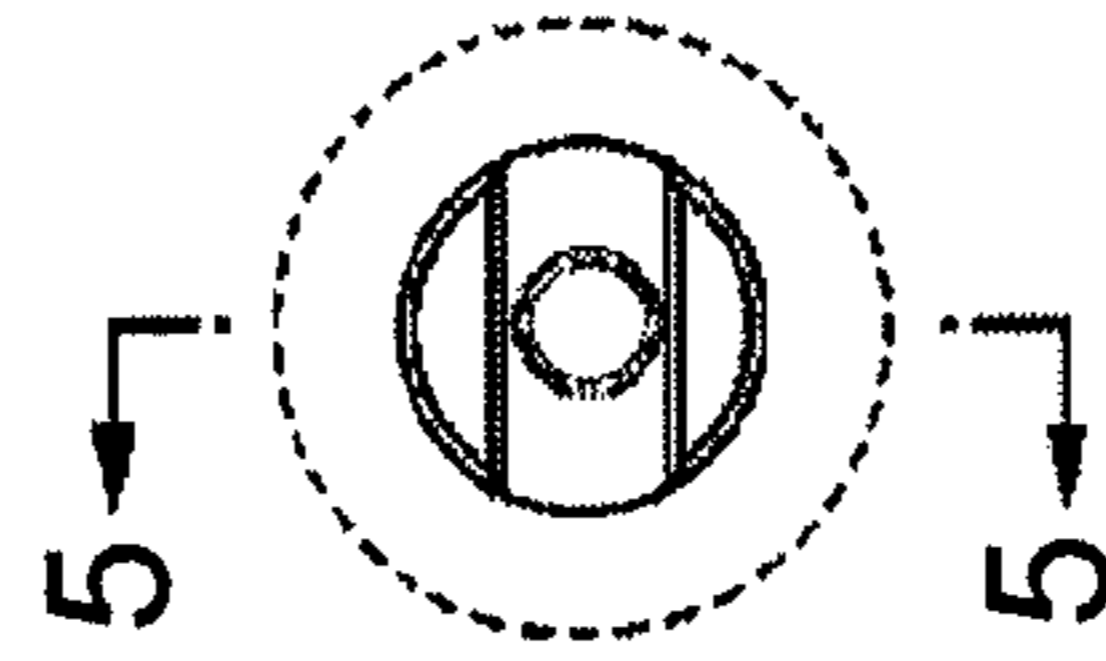


FIG.1

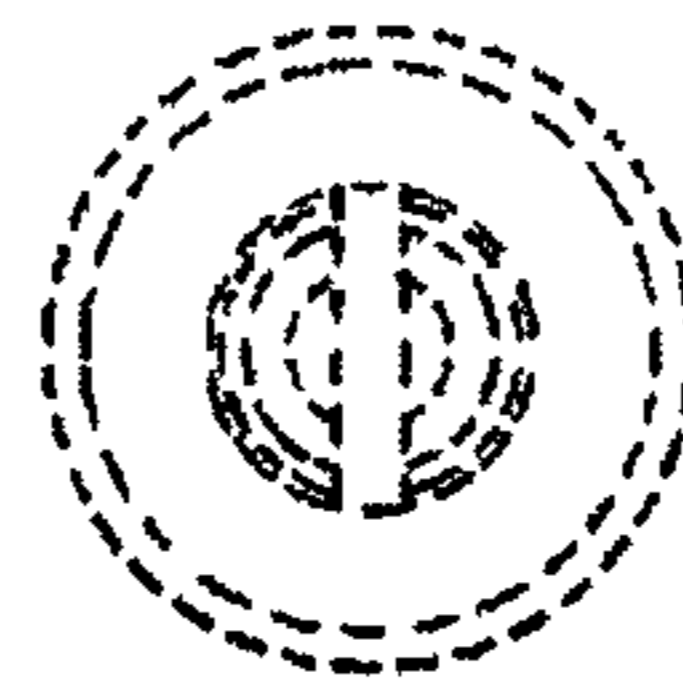


FIG.2

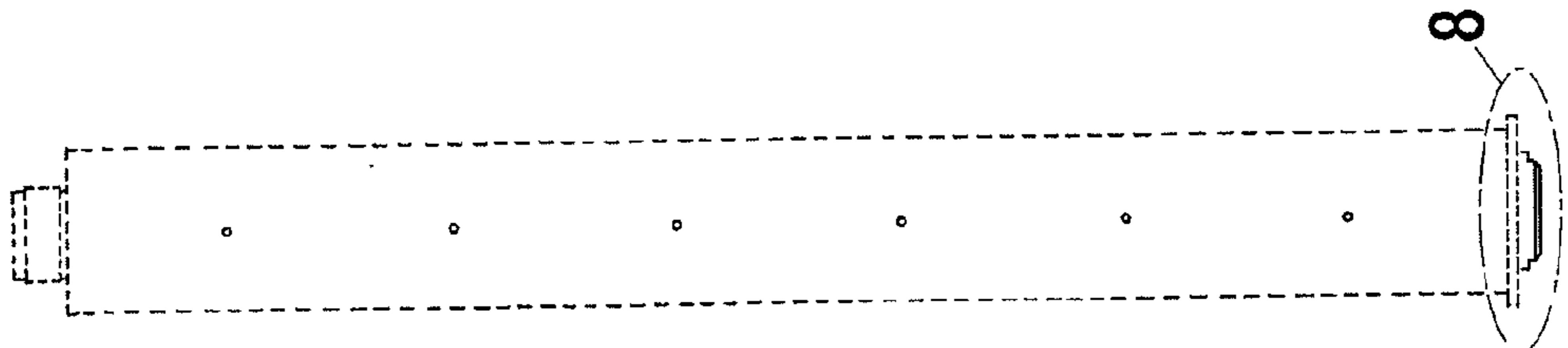


FIG. 3

FIG. 4

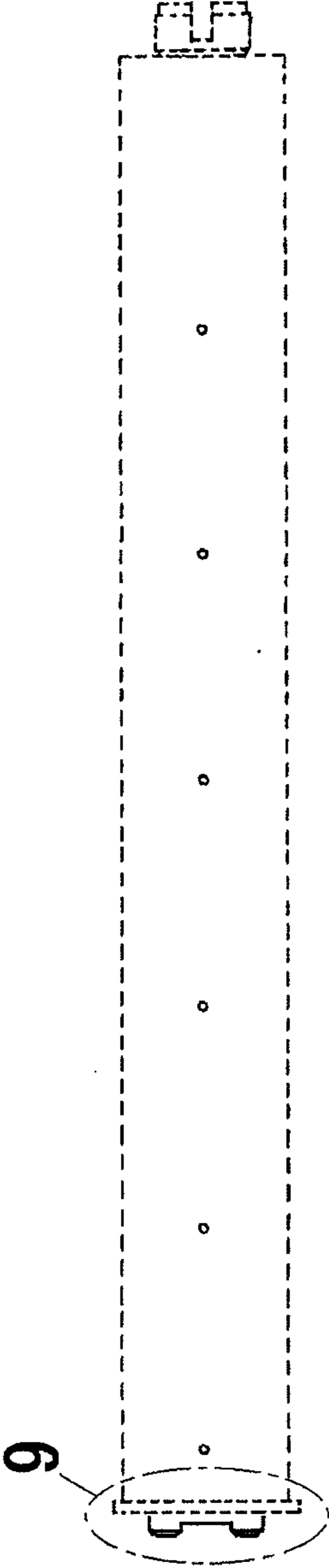
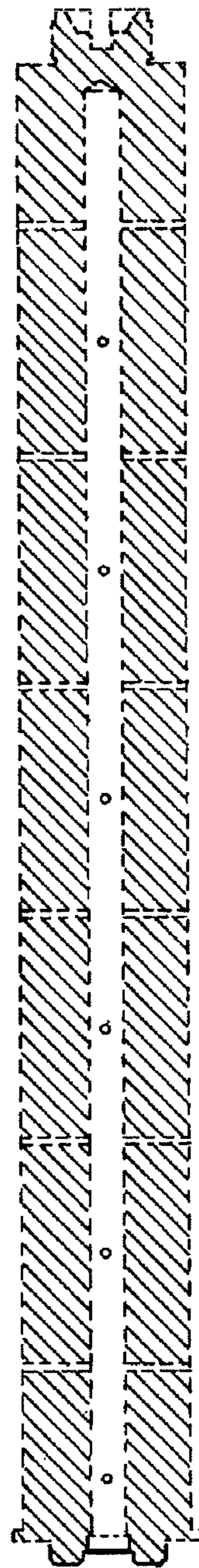


FIG.5



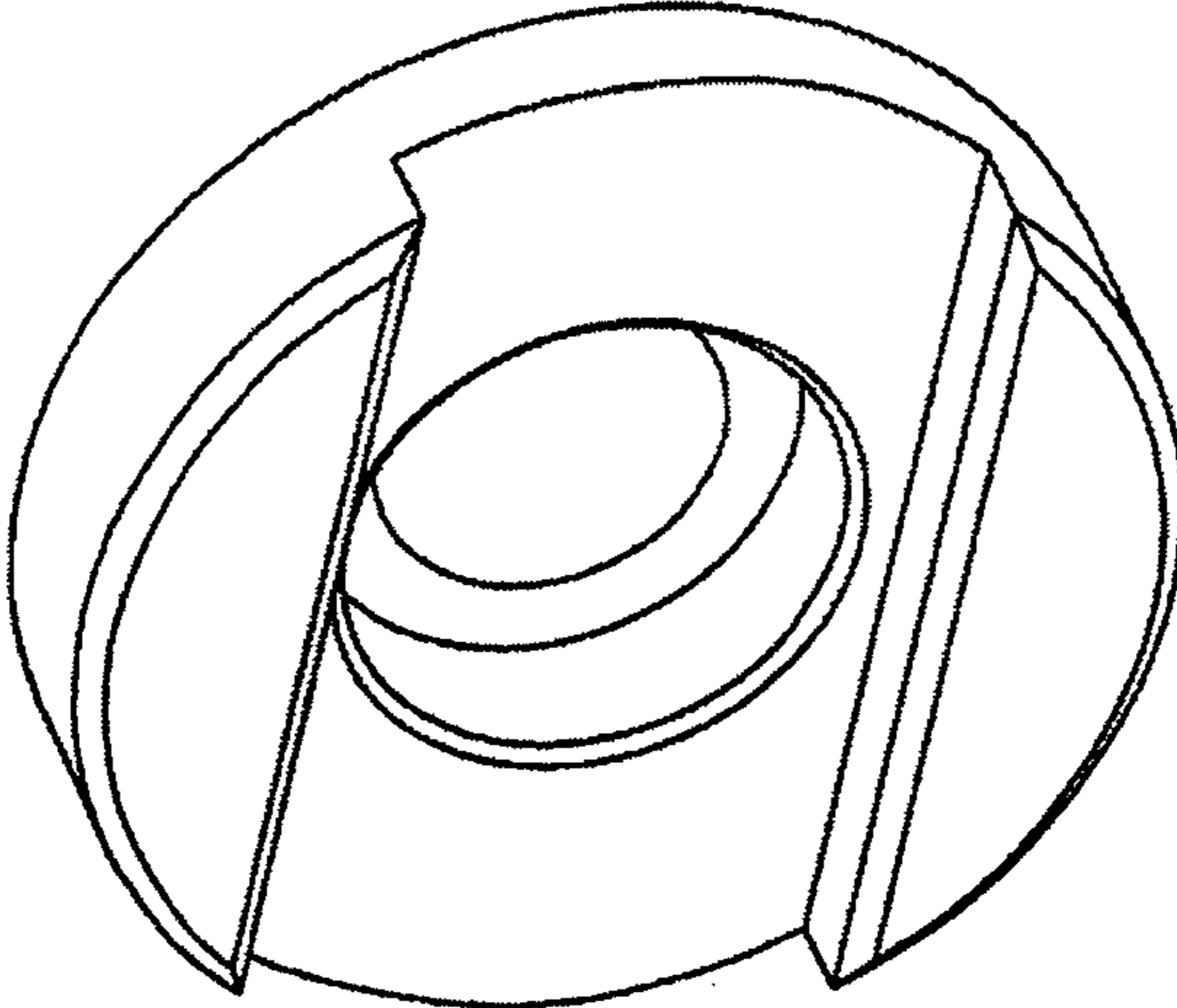


FIG.6

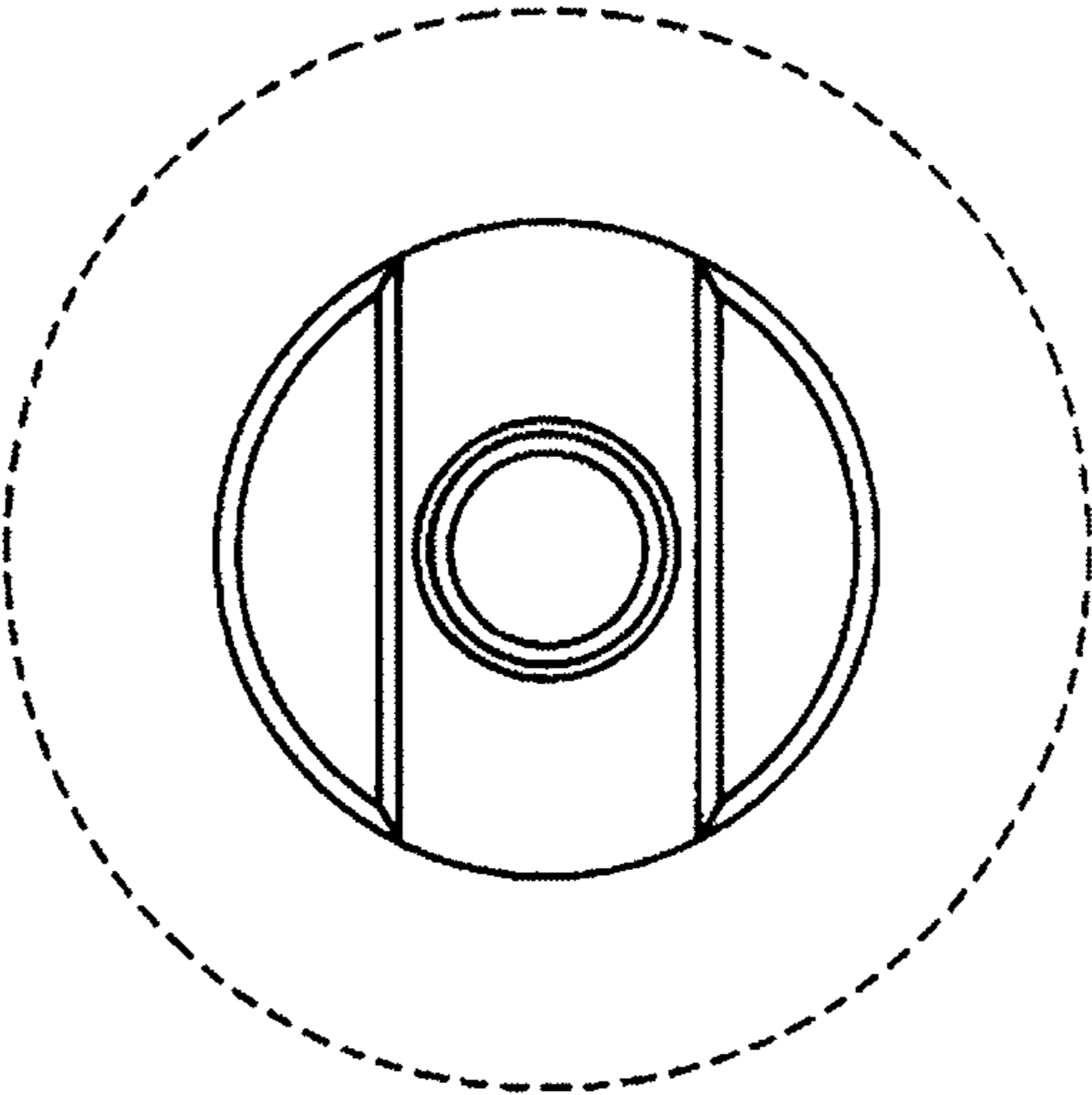


FIG.7

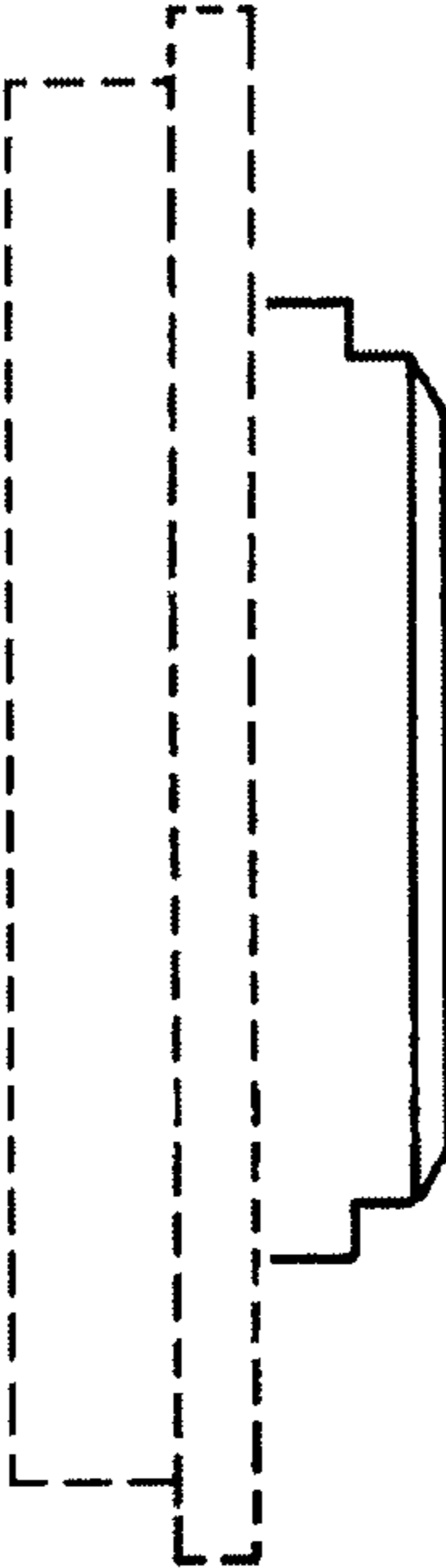


FIG.8

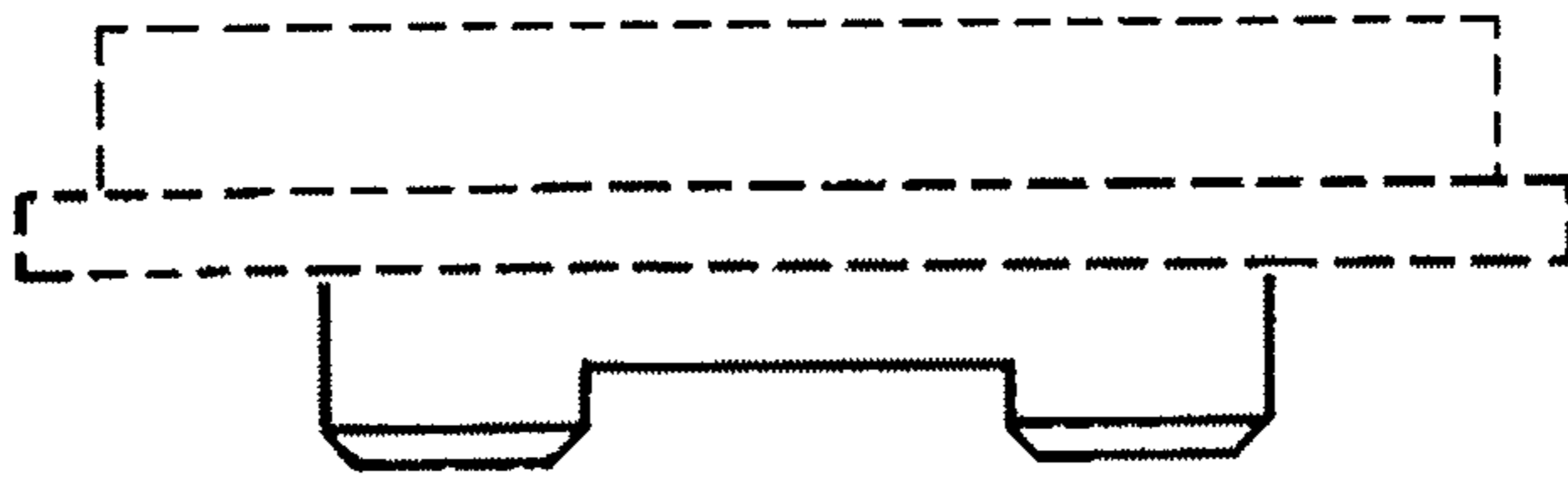


FIG.9